

Optical Instrument Thermal Control on the Large Ultraviolet/Optical/Infrared Surveyor

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What is LUVOIR?

- The Large Ultraviolet/ Optical/ Infrared Surveyor (LUVOIR) is a multiwavelength general-purpose space observatory
 - One of four concept studies for the 2020 Decadal Survey in Astronomy / Astrophysics
- LUVOIR enables broad range of astrophysics to be performed:
 - Galaxy and planet evolution
 - Star and planet formation
 - Exoplanet atmospheric and surface composition (assessing habitability, biosignatures) to answer question "are we alone?"
- LUVOIR operates at Sun-Earth Lagrange Point 2 orbit









LUVOIR's Instruments



- Extreme Coronagraph for Living Planetary Systems (ECLIPS): Coronagraph with imaging, integral-field spectroscopy, and point-source spectroscopy capabilities
 - 200 nm 2.0 µm bandpass; Ultraviolet (UV), Visible (VIS), Near-Infrared (NIR) channels
- **High Definition Imager (HDI):** wide field-of-view camera with Imaging, GRISM Spectroscopy, Fine Guiding, Phase Retrieval, and Astrometric capabilities
 - 200 nm 2.5 μm bandpass, UV/VIS, Near-IR channels
- LUVOIR UV Multi-Object Spectrograph (LUMOS): multiobject spectroscopy and imaging
 - 100 nm 1.0 µm bandpass; Far-UV, Near-UV, VIS channels
- Pollux: spectropolarimetry and pure spectroscopy capabilities (Centre National d' Études Spatiales)
 - 100 nm 390 nm bandpass; Far-UV, Mid-UV, Near-UV channels







LUMOS

Pollux

Two LUVOIR Concepts





Instrument Layout





Instrument Thermal Design Requirements



| | ECLIPS | HDI | LUMOS |
|-------------------------------------|--|---|--|
| 270 K - 280 K Zone Components | Optical Benches, UV/VIS Front End Electronics (FEE); Main Electronics Box (MEB), Control System Processor (CSP) (all 270 K) | UV/VIS Optical Bench and components; MEB (all 270 K) | Optical Bench; FUV: Multi-Object Spectrograph (MOS), Imager, FEEs; MEB, Microshutter Array (MSA), LUMOS Microshutter Control Electronics (LMCE), High-Voltage Power Source (HVPS) (all 280 K) |
| 270 K Zone Temperature Stability | ± 0.5 K benches and FEEs; ±1 K electronics | ± 0.5 K benches; no requirement for electronics | ± 3 K FUV and benches; no requirement for electronics |
| 170 K Zone Components | NIR Low-Order Wavefront Sensor (LOWFS); VIS: Imager, LOWFS, Integral Field Spectrograph (IFS); UV: Imager, LOWFS; all NIR FEES | NIR: FEE, Filter Wheel (FW), and mirrors; UV/VIS: Focal Plane Assembly (FPA) and FEE | NUV MOS |
| 170 K Zone Temperature Stability | ± 0.5 K | ± 0.005 K UV/VIS FPA, ± 0.5 K all others | ± 0.1 K |
| 100 K Zone Components | NIR IFS, NIR Single Planet Spectrograph (SPS) | NIR FPA | |
| 100 K Zone Temperature Stability | ± 0.5 K | ± 0.01 K | |

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Instrument Thermal Design Overview

- Optical benches are actively heated
 - Instruments reside in a warm sink environment provided by the actively-heated BSF panels
- Components reject their heat with Oxygen-Free High Conductivity (OFHC) copper heat straps, which interface with Constant Conductance Heat Pipes (CCHPs) to transport heat to the radiators
 - 100 K components use Nitrogen CCHPs to 80 K radiator on +V3 side of BSF
 - 170 K components use Ethane CCHPs to 150 K radiator on \pm V2 sides of BSF
 - 270 K components use Ammonia CCHPs to 250 K radiator on ±V2 sides of BSF
 - All heat pipes arrayed in V2/V3 plane for ease of testing
- Blanket tent around each instrument
- Detectors are cold-biased and actively heated
- Decontamination heaters for each detector



ECLIPS Detailed Thermal Block Diagram



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HDI Detailed Thermal Block Diagram



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LUMOS Detailed Thermal Block Diagram



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LUVOIR

Preliminary Thermal Analysis: Heater Power



| | ECLIPS- A | ECLIPS- B | LUMOS- A | LUMOS- B | HDI-A | HDI-B |
|---|--------------|--------------|-------------|-------------|-------|-------|
| Operational Heater Power for Electronics Boxes and Optical Components (W) | 23.5 | 23.5 | 88.2 | 77.5 | 29.4 | 8.2 |
| Operational Heater Power for Optical Benches (W) | 28.4 | 28.4 | 109.0 | 77.0 | 49.3 | 28.2 |
| Decontamination Heater Power (W) | 6.4 | 6.4 | 76.4 | 61.8 | 56.7 | 22.9 |
| Survival Heater Power (W) | 58.4 | 58.4 | 331.7 | 221.7 | 112.1 | 44.4 |

- 40% uncertainty margin added for heater powers
- Relatively small optical bench heater powers considering their size, due to warm sink provided by actively heated BSF
 - LUMOS has higher heater power due to setpoint at 280 K for contamination avoidance
- For electronics boxes and optical components: heater powers estimated based on desired operational temps and to compensate for heat lost to radiators if not dissipating at max value

Preliminary Thermal Analysis: Heat to Radiator and Radiator Area



| | ECLIPS -A | ECLIPS -B | LUMOS- A | LUMOS- B | HDI-A | HDI-B |
|---|--------------|--------------|-------------|-------------|-------|-------|
| Total Heat to 80 K Radiator (W) | 0.3 | 0.3 | | | 3.2 | 3.1 |
| Total Heat to 150 K Radiator (W) | 14.0 | 14.0 | 36.3 | 11.9 | 68.0 | 48.0 |
| Total Heat to 250 K Radiator (W) | 407.4 | 407.4 | 329.3 | 238.9 | 99.9 | 96.0 |
| Total 80 K Instrument Radiator Area (m ²) | 0.3 | 0.2 | | | 4.1 | 2.2 |
| Total 150 K Instrument Radiator Area (m ²) | 0.8 | 1.1 | 2.1 | 0.9 | 4.0 | 3.7 |
| Total 250 K Instrument Radiator Area (m ²) | 2.1 | 2.1 | 1.7 | 1.2 | 0.5 | 0.5 |

• Heat dissipation margin 50% for 170 K components, 100% for 100 K components

- BSF contains enough surface area in both concepts for fixed radiators
 - No deployables necessary

Conclusions and Recommendations



- Thermal design has been presented for instruments in both LUVOIR observatory concepts
 - Each instrument is enclosed within warm BSF
 - Three general thermal zones: 100 K, 170 K, 270-280 K
 - Series of heaters on each instrument drive components and optical benches to operational temperatures
 - Each thermal zone has its won dedicated transport heat pipes to corresponding radiators
 - LUVOIR-A requires significantly more heater power than LUVOIR-B, but power does not just scale with size of observatory
- For future development of LUVOIR:
 - Heat transport system design needs to be matured; more detailed quantification of parasitic heat leaks into heat pipes required
 - Verification of thermal design is critical to LUVOIR's success: extensive thermal analysis and test planning required to ensure instruments are being tested in flight-like condition, including considerations of heat pipe levelness and cross-talk between instruments and BSF

List of Acronyms (1)



| AOS | Aft Optics System | FUV | Far Ultraviolet |
|--------|---|--------|--|
| BK | Black Kapton coating | FW | Filter Wheel |
| BSF | Backplane Support Frame | GSFC | NASA Goddard Space Flight Center |
| ССНР | Constant Conductance Heat Pipe | GW | Grating Wheel |
| CSM | Channel Select Mechanism | HDI | High Definition Imager |
| CTE | Coefficient of Thermal Expansion | HVPS | High-Voltage Power Source |
| ΔT | Change in temperature | IFS | Integral Field Spectrograph |
| DM | Deformable Mirror | IM | Imager Mirror |
| ECLIPS | Extreme Coronagraph for Living Planetary Systems | IR | Infrared |
| FC | Field Corrector | IS | Image Surface |
| FEE | Front-End Electronics | LMCE | LUMOS Microshutter Control Electronics |
| FM | Fold Mirror | LOWFS | Low-Order Wavefront Sensor |
| FPA | Focal Plane Assembly | LUMOS | LUVOIR Ultraviolet Multi-object Spectrograph |
| FPM | Focal Plane Mask | LUVOIR | the Large Ultraviolet/Optical/Infrared Surveyor |
| FSM | Fast Steering Mirror | К | Kelvin |

List of Acronyms (2)



| m | Meter | PMBSS | Primary Mirror Backplane Support Structure |
|------|---|---------|--|
| MEB | Main Electronics Box | PR, PRM | |
| MLI | Multi-Layer Insulation | RM | Relay Mirror |
| MOS | Multi-object Spectrograph | ROSA | Roll-Out Solar Array |
| MSA | Micro-Shutter Array | SC | Spacecraft |
| NASA | National Aeronautics and Space Administration | SLI | Single-Layer Insulation |
| ND | Neutral Density | SM | Secondary Mirror |
| NIR | Near-Infrared | SMSS | Secondary Mirror Support Structure |
| NUV | Near-Ultraviolet | SPS | Single Planet Spectrograph |
| ΟΑΡ | Off-Axis Parabola | ТМ | Tertiary Mirror |
| OFHC | Oxygen-Free High Conductivity copper | ULE | Ultra Low Expansion glass |
| ΟΤΑ | Optical Telescope Assembly | UV | Ultraviolet |
| PAS | Payload Articulation System | UVIS | Ultraviolet /Visible |
| PID | Proportional-Integral-Derivative Control | VDA | Vapor-Deposited Aluminum coating |
| PDU | Power Distribution Unit | VIS | Visible light |
| РМ | | W | Watt(s) |